

INFORMATION DISCLOSURE STATEMENT BY APPLICANT

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| Application Number | 10/528,376 |
| Filing Date | December 5, 2005 |
| First Named Inventor | Masamichi MORITA |
| Art Unit | 1794 |
| Examiner Name | Gerard T. Higgins |
| Attorney Docket Number | Q86778 |

U.S. PATENTS

| Examiner Initials* | Cite No | Patent Number | Kind Code ¹ | Issue Date | Name of Patentee or Applicant of cited Document | Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear |
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| | 1 | 20020081520 | A1 | 2002-06-27 | SOORIYAKUMARAN et al. | |

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| Examiner Initials* | Cite No | Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city, and/or country where published. | T ⁵ |
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EXAMINER SIGNATURE

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